

Serial No. 09/881,254

CLAIM AMENDMENTS:

1. (Cancelled)

2. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein said body region is separated from said source metal by said source region.

3. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, further comprising gate metal adjacent said conductive region.

4. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein the body region further comprises a material that provides generation-recombination centers.

5. (Original) The trench MOSFET transistor device of claim 4, wherein said material is selected from gold and platinum.

6. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein said source, drain and body regions are doped silicon regions.

7. (Original) The trench MOSFET transistor device of claim 6, wherein said conductive region is doped polycrystalline silicon.

8. (Original) The trench MOSFET transistor device of claim 6, wherein said insulating layer is a silicon dioxide layer.

9. (Original) The trench MOSFET transistor device of claim 6, wherein said insulating layer is a silicon oxynitride layer.

Serial No. 09/881,254

10. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein a fixed charge is provided within said insulating layer.

11. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein said source and drain regions have peak net doping concentrations that are greater than a peak net doping concentration of said body region.

12. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein said first conductivity type is N-type conductivity and said second conductivity type is P-type conductivity.

13. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein said source and drain regions comprise the same dopant material.

14. (Cancelled)

15. (Currently amended) The trench MOSFET transistor device of ~~claim 14~~ claim 28, wherein said doping material comprises arsenic.

16. (Currently amended) The trench MOSFET transistor device of ~~claim 14~~ claim 28, wherein said doping material comprises phosphorous.

17-24. (cancelled)

25. (Currently amended) The trench MOSFET transistor device of ~~claim 1~~ claim 27, wherein said trench MOSFET transistor device comprises a plurality of source regions which are shorted to one another.

26. (Currently amended) The trench MOSFET transistor device of ~~claim 14~~ claim 28, wherein said trench MOSFET transistor device comprises a plurality of source regions which are shorted to one another.

Serial No. 09/881,254

27. (Currently amended) A The trench MOSFET transistor device of claim 1 comprising:
a drain region of a first conductivity type;
a body region of a second conductivity type provided over said drain region, said
drain region and said body region forming a first junction;
a source region of said first conductivity type provided over said body region, said
source region and said body region forming a second junction;
source metal disposed on an upper surface of said source region;
a trench extending through said source region, through said body region and into
said drain region; and
a gate region comprising an insulating layer lining at least a portion of said trench
and a conductive region within said trench adjacent said insulating layer,
wherein (a) said body region is separated from said source metal, and (b) a doping
profile along a line normal to upper and lower surfaces of said device is such that, (i) the
doping profile is non-uniform within the body region, (ii) within said body region and
within at least a portion of said source and drain regions, the doping profile on one side of
a centerplane of the body region is substantially symmetric with the doping profile on an
opposite side of the centerplane, and (iii), wherein said the doping profile comprises a
substantially peaked central region.

28. (Currently amended) A The trench MOSFET transistor device of claim 14
comprising:
a silicon drain region of N-type conductivity;
a silicon body region of P-type conductivity provided over said drain region, said
drain region and said body region forming a first junction;
a silicon source region of N-type conductivity provided over said body region,
said source region and said body region forming a second junction;
source metal disposed on an upper surface of said source region;
a trench extending through said source region, through said body region and into
said drain region; and

Serial No. 09/881,254

a gate region comprising a silicon dioxide layer lining at least a portion of said trench and a doped polycrystalline silicon region within said trench adjacent said silicon dioxide layer,

wherein (a) said body region is separated from said source metal by said source region, (b) said source and drain regions comprise the same doping material, (c) said source and drain regions have peak net doping concentrations that are greater than a peak net doping concentration of said body region, and (d) a doping profile along a line normal to upper and lower surfaces of said device is such that, (i) the doping profile is non-uniform within the body region, (ii) within said body region and within at least a portion of said source and drain regions, the doping profile on one side of a centerplane of the body region is substantially symmetric with the doping profile on an opposite side of said centerplane, and (iii), wherein said the doping profile comprises a substantially peaked central region.